

ABSTRACT

**METHOD FOR MANUFACTURING MAGNETIC-DISK SUBSTRATE, AND
POLISHING PAD USED IN MANUFACTURE OF MAGNETIC-DISK
SUBSTRATE**

In order to reduce a root mean square roughness R_q of microwaviness having a wavelength from 50 to 200 μm on a main surface of a glass substrate, a method for manufacturing a magnetic-disk substrate includes polishing both main surfaces of a substrate by sandwiching the substrate with a pair of polishing pads, supplying a slurry containing polishing abrasive particles between the polishing pads and the substrate, and sliding the polishing pads and the substrate relative to each other. The polishing pads respectively have a resin foam layer having a plurality of openings in a surface. When information on a three-dimensional shape of a surface of the polishing pads is obtained from captured images of the surface of the polishing pads, and an arithmetic mean roughness R_a of the surface of the polishing pads is derived from the information on the three-dimensional shape, the R_a is 0.5 μm or less.

(Figure 4)